

Application News Gas Chromatography

No. **G300**

Analysis of SF₆ Insulation Gas Using a GC-BID System

Sulfur hexafluoride (SF₆) is an extremely stable gas with excellent dielectric properties and is used in various fields. Applications include tracer gas as well as insulation gas used in electrical equipment such as gas-insulated transformers and circuit breakers. On the other hand, SF₆ is also known to be a highly potent greenhouse gas and was identified as an emission reduction target in the Kyoto Protocol at the COP3 meeting. Conventional analysis of SF₆ employs an electron capture detector (ECD) which is capable of detecting electrophilic compounds with high sensitivity. However, the quantitation accuracy in the high-concentration range and the hassle of procedures necessary due to the use of radioisotopes have been an issue. Shimadzu's barrier discharge ionization detector (BID) offers high-sensitivity detection of almost all components. Utilizing proprietary barrier discharge technology, the detector achieves both the same stability as general conventional detectors and high sensitivity.

This article introduces example analyses of SF_6 and SF_6 decomposition products.

R. Kubota, S. Uchiyama

Analysis of Impurities in SF₆

 SF_6 is used as an insulation gas in various electrical equipment and requires purity analysis for quality control to maintain insulation properties and when recycling the gas. Fig. 1 shows the result of analyzing impurities in SF_6

using a BID. The primary component SF₆ is saturated, but did not influence the quantitation accuracy of surrounding components, showing that high-sensitivity batch analysis of impurities including inorganic gas and lower hydrocarbons was successful. (Under the analytical conditions using this type of column, C₂H₆ is overlapped by SF₆.)

The concentrations of impurities found in the SF_6 sample are as follows.

H_2 :	0.9 ppm	CO :	0.9 ppm	CH₄:	1.7 ppm
CO ₂ :	21 ppm	N_2O :	2.0 ppm	C_2H_2 :	2.4 ppm
C_2H_4 :	1.4 ppm	C_3H_6 :	1.0 ppm	C_3H_8 :	1.0 ppm

Table 1 Measurement Conditions

Model	: Nexis™ GC-2030
Detector	: BID-2030
Inj. Mode	: Split 1:4
Inj.Temp.	: 150 °C
Carrier Gas	: 7 mL/min (constant flow rate)
Column	: MICROPACKED-ST 2.0 m × 1.0 mm l.D.
	(Input 250 m \times 0.50 mm I.D. and df = 10 μ m for flow
	rate calculation)
Column Temp.	: 35 °C (2.5 min) – 20 °C/min – 250 °C (0 min) –
	15 °C/min – 265 °C (3.0 min)
Purge flow	: 3 mL/min
Det. Temp.	: 280 °C
Discharge Gas	: 50 mL/min (He)
Inj. Volume	: 3.0 mL (MGS-2030)

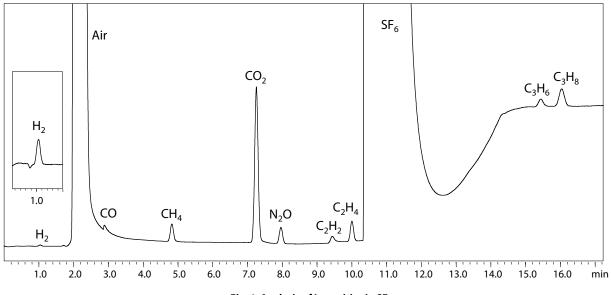


Fig. 1 Analysis of Impurities in SF₆

Analysis of Trace SF₆ in the Atmosphere

Since SF_6 is a potent greenhouse gas and its emission into the atmosphere must be avoided, leak tests for insulation gas from electrical equipment and residue tests after collecting gas may require analysis of trace amounts of SF_6 . Table 2 lists the measurement conditions and Fig. 2 shows the result of analyzing trace SF_6 in the atmosphere.

 SF_6 at a concentration of 0.1 ppm was detected (S/N = 24^{*1}) and favorable linearity was obtained in the range from 0.1 to 50 ppm ($R^2 = 0.9998$).

*1 Determined by calculating noise from the baseline between 0.5 and 1.5 min.

Table 2 Measurement Conditions

Model	: Nexis ™ GC-2030
Detector	: BID-2030
Inj. Mode	: Split 1:7
lnj.Temp.	: 150 °C
Carrier Gas	: 45 cm/sec (constant linear velocity)
Column	: SH-Rt [™] -Msieve 5A (0.53 mm l.D.×30 m, d.f.50 μm)
Column Temp.	: 35 °C (2.5 min) – 20 °C/min – 250 °C (0 min) –
	15 °C/min – 270 °C (3.42 min)
Purge flow	: 3 mL/min
Det. Temp.	: 280 °C
Discharge Gas	: 50 mL/min (He)
Inj. Volume	: 3.0 mL (MGS-2030)

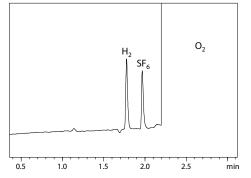


Fig. 2 Analysis of Trace SF₆ (0.1 ppm) in the Atmosphere

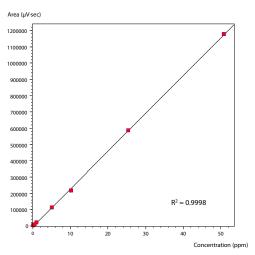


Fig. 3 Linearity of SF₆ in the Atmosphere (0.1 to 50 ppm)

Analysis of SF₆ Decomposition Gas

SF₆ is used as an insulation gas in circuit breakers. Breakers are installed on electrical grids to shut off high voltages that may occur due to causes such as lightning strikes. When performing maintenance on such breakers, SF₆ decomposition gases are analyzed to judge the degradation level of insulation gas. Table 3 lists the measurement conditions and Fig. 4 shows the results of an example analysis of CF₄ and SOF₂ which are SF₆ decomposition gases. Sample injection using a gas sampler and a gas-tight syringe is possible on the same system, allowing analysis of gas samples in various forms and concentrations.

able 3	S N	leasure	ment	Cond	itions

Т

		Tuble 5 Medsarement conditions
	Model	: Nexis [™] GC-2030
	Detector	: BID-2030
	Inj. Mode	: Split 1:4
	Inj.Temp.	: 150 °C
	Carrier Gas	: 7 mL/min (constant flow rate)
	Column	: MICROPACKED-ST 1.0 m × 1.0 mm I.D.
		(Input 1,250 m $ imes$ 0.50 mm I.D. and df = 15 μ m for
		flow rate calculation)
	Column Temp.	: 50 °C (1.0 min)– 25 °C/min – 150 °C (0 min) –
		5 °C/min – 200 °C (0 min)
	Purge flow	: 3 mL/min
	Det. Temp.	: 280 °C
	Discharge Gas	: 50 mL/min (He)
	Inj. Volume	: 200 μL (gas-tight syringe)
1		

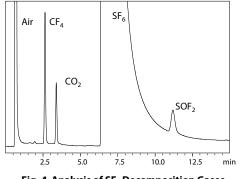


Fig. 4 Analysis of SF₆ Decomposition Gases (CF₄: 310 ppm, SOF₂: 107 ppm)

Nexis is a trademark of Shimadzu Corporation. Rt is a trademark of Restek Corporation.

First Edition: Mar. 2018



Shimadzu Corporation www.shimadzu.com/an/

For Research Use Only. Not for use in diagnostic procedure.

This publication may contain references to products that are not available in your country. Please contact us to check the availability of these products in your country.

The content of this publication shall not be reproduced, altered or sold for any commercial purpose without the written approval of Shimadzu. Shimadzu disclaims any proprietary interest in trademarks and trade names used in this publication other than its own. See http://www.shimadzu.com/about/trademarks/index.html for details.

The information contained herein is provided to you "as is" without warranty of any kind including without limitation warranties as to its accuracy or completeness. Shimadzu does not assume any responsibility or liability for any damage, whether direct or indirect, relating to the use of this publication. This publication is based upon the information available to Shimadzu on or before the date of publication, and subject to change without notice.